SEARCH REQUEST FORM Scientific and Technical Information Center

Requester's Full Name: Sin J. Lee Examiner #: 760 60 Date: 2-9-05 Art Unit: 1052 Phone Number 36 2-1333 Serial Number: 10/691/8 75 Mail'Box and Bldg/Room Location: 9 D 6 Results Format Preferred (circle) PAPER DISK E-MAIL (Rem.) If more than one search is submitted, please prioritize searches in order of need.							
Please provide a detailed statement of the s Include the elected species or structures, ke	earch topic, and describe a cywords, synonyms, acron that may have a special me	*********************************** Is specifically as possible the subject matter to be sear yms, and registry numbers, and combine with the con- aning. Give examples or relevant citations, authors, e	cept or				
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Title of Invention: Inventors (please provide full names):							
Earliest Priority Filing Date:		SCIENTIFIC REFERENCE BR Sci. & Tech. Info. Critr	· .				
For Sequence Searches Only Please includ	· · · · · · · · · · · · · · · · · · ·	 parent, child, divisional, or isshed Bathi humbers) along v	vith the				
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STAFF USE ONLY Searcher: EL	Type of Search	Vendors and cost where applicable					
Searcher: CG	NA Sequence (#)	STN					
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Date Completed: 2-10-05	Litigation	Lexis/Nexis	_				
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Online Time:	Other	Other (specify)					

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BIBDATASHEET

CONFIRMATION NO. 8992

Bib Data Sheet						
SERIAL NUMBER 10/697,875	FILING DATE 10/31/2003 RULE	CLASS 430	GROUP ART 1752	'	ATTORNEY DOCKET NO. 2003_1587A	
APPLICANTS Kazuhiro Machiguchi, Osaka, JAPAN; Masanori Shinada, Osaka, JAPAN; Yuuji Ueda, Osaka, JAPAN;Hiroki Endo, Tokyo, JAPAN; Taichi Natori, Tokyo, JAPAN; ** CONTINUING DATA **********************************						
IF REQUIRED, FORE ** 02/02/2004 Foreign Priority claimed 35 USC 119 (a-d) conditions met Verified and	Allowance	STATE OR	SHEETS DRAWING 2	TOTAL CLAIMS 12	INDEPENDENT CLAIMS 1	
ADDRESS 000513 WENDEROTH, LIND & PONACK, L.L.P. 2033 K STREET N. W. SUITE 800 WASHINGTON, DC 20006-1021						
TITLE Colored photosensitive resin composition and color filter comprising the same						
FILING FEE FEES: Authority has been given in Paper			☐ <u>1.1</u>	All Fees 1.16 Fees (Filing) 1.17 Fees (Processing Ext. of		

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=> file reg FILE 'REGISTRY' ENTERED AT 18:35:47 ON 10 FEB 2005 USE IS SUBJECT TO THE TERMS OF YOUR STN CUSTOMER AGREEMENT. PLEASE SEE "HELP USAGETERMS" FOR DETAILS. COPYRIGHT (C) 2005 American Chemical Society (ACS)

=> display history full 11-

	FILE 'REGI	STRY' ENTERED AT 17:17:02 ON 10 FEB 2005 E STYRENE/CN
L1	1	SEA STYRENE/CN
L2	•	SEA 100-42-5/CRN
		E 4-HYDROXYSTYRENE/CN
L3	1	SEA 4-HYDROXYSTYRENE/CN
L4	1850	SEA 2628-17-3/CRN
L5	181	SEA L2 AND L4
L6	4	SEA L5 AND 2/NC
		ENTERED AT 17:18:39 ON 10 FEB 2005
L7		SEA L6
$\Gamma8$		SEA (COLOR? OR COLOUR?) (2A) FILT?
L9	91809	SEA ((PHOTO OR LIGHT OR PHOTOLY?)(2A)(RX# OR RXN# OR
		REACT? OR SENSITI? OR POLYM? OR CURE# OR CURING# OR
		CURAB? OR CROSSLINK? OR CROSS(W)LINK? OR CAT# OR
T 1 O	102102	CATALY?))/BI,AB
ПТО	102192	SEA ((ULTRAVIOLET? OR ULTRA(W)VIOLET? OR UV# OR SUV OR LUV OR RADIA? OR IRRADIA? OR EMANAT? OR EMIT? OR EMISS?
		OR LASER?) (2A) (RX# OR RXN# OR REACT? OR REACT? OR POLYM?
٠		OR CURE# OR CURING# OR CURAB? OR CAT# OR CATALY? OR
		CROSS(W)LINK? OR CROSSLINK?))/BI,AB
L11	164410	SEA (PHOTORX## OR PHOTOREACT? OR PHOTOSENS? OR PHOTOPOLYM
		? OR PHOTOCUR? OR PHOTOHARDEN? OR PHOTOCROSS? OR
		PHOTOCAT?)/BI,AB
L12	158219	SEA RESIST OR RESISTS OR PHOTORESIST? OR MASK? OR
		PHOTOMASK?
L13	10	SEA L7 AND L8
L14	164	SEA L7 AND L12
L15	70	SEA L7 AND (L9 OR L10 OR L11)
L16		SEA L14 AND L15
L17	1	SEA L13 AND L16
	FILE 'HCAPI	LUS' ENTERED AT 18:00:27 ON 10 FEB 2005
L18		SEA MACHIGUCHI ?/AU
L19		SEA SHINADA ?/AU
L20		SEA UEDA ?/AU

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L21 2081 SEA NATORI ?/AU
L22
            0 SEA L18 AND L19 AND L20 AND L21
L23
             0 SEA L18 AND L19
L24
           11 SEA L18 AND L20
            4 SEA L18 AND L21
L25
L26
            12 SEA L19 AND L20
           0 SEA L19 AND L21
5 SEA L20 AND L21
L27
L28
           5 SEA L20 AND L21
24 SEA (L23 OR L24 OR L25 OR L26 OR L27 OR L28)
L29
            1 SEA L29 AND L12
L30
           11 SEA L29 AND ((L8 OR L9 OR L10 OR L11 OR L12))
L31
               SEL L31 1-11 RN
     FILE 'REGISTRY' ENTERED AT 18:05:56 ON 10 FEB 2005
            79 SEA (68-12-2/BI OR 22374-89-6/BI OR 107-45-9/BI OR
L32
L33
             6 SEA L32 AND PMS/CI
               D L33 1-6 RN IN
               SEL L33 3,6 RN
L34
             2 SEA (24979-74-6/BI OR 72317-19-2/BI)
L35
             1 SEA L34 AND L6
     FILE 'HCA' ENTERED AT 18:08:01 ON 10 FEB 2005
          439 SEA L34
L36
L37
           12 SEA L36 AND L8
           222 SEA L36 AND L12
L38
L39
           99 SEA L36 AND (L9 OR L10 OR L11)
            11 SEA L37 AND (L38 OR L39)
L40
L41
            80 SEA L38 AND L39
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              E 2-HYDROXYSTYRENE/CN
L42
             1 SEA 2-HYDROXYSTYRENE/CN
               D RN
           35 SEA 695-84-1/CRN
               E 3-HYDROXYSTYRENE/CN
L44
            1 SEA 3-HYDROXYSTYRENE/CN
               D RN
L45
          129 SEA 620-18-8/CRN
L46
           10 SEA (L43 OR L45) AND L2
L47
            3 SEA L46 AND 2/NC
    FILE 'HCA' ENTERED AT 18:10:35 ON 10 FEB 2005
            55 SEA L47
L48
L49
             0 SEA L48 AND L8
L50
            20 SEA L48 AND L12
L51
            3 SEA L48 AND (L9 OR L10 OR L11)
L52
          3 SEA L50 AND L51
L53 462071 SEA FILTER?
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L54
              5 SEA L14 AND L53
L55
             5 SEA L15 AND L53
L56
             1 SEA L16 AND L53
L57
             6 SEA L38 AND L53
L58
             7 SEA L39 AND L53
L59
             0 SEA L50 AND L53
L60
             0 SEA L51 AND L53
           11 SEA (L54 OR L55 OR L56 OR L57 OR L58 OR L59 OR L60)
L61
L62
           15 SEA L13 OR L17 OR L37 OR L40 OR L52 OR L61
            51 SEA L16 NOT L62
L63
L64 ·
           50 SEA L63 AND (1900-2002/PY OR 1900-2002/PRY)
L65
            15 SEA L62 AND (1900-2002/PY OR 1900-2002/PRY)
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=> file hca FILE 'HCA' ENTERED AT 18:36:03 ON 10 FEB 2005 USE IS SUBJECT TO THE TERMS OF YOUR STN CUSTOMER AGREEMENT. PLEASE SEE "HELP USAGETERMS" FOR DETAILS. COPYRIGHT (C) 2005 AMERICAN CHEMICAL SOCIETY (ACS)

=> d 165 1-15 cbib abs hitstr hitind

L65 ANSWER 1 OF 15 HCA COPYRIGHT 2005 ACS on STN

141:44989 Colored light-sensitive resin composition
for color filters in CCD camera. Machiguchi,
Kazuhiro; Shinata, Masanori; Ueda, Yuji; Endo, Hirotake; Natori,
Taichi (Sumitomo Chemical Co., Ltd., Japan; Sony Corp.). Jpn. Kokai
Tokkyo Koho JP 2004170953 A2 20040617, 15 pp. (Japanese). CODEN:
JKXXAF. APPLICATION: JP 2003-370254 20031030. PRIORITY: JP
2002-319505 20021101.

AB The title compn. contains an alkali-solubilizable copolymer, wherein the copolymer contains a repeating unit derived from hydroxystyrene and repeating unit derived from styrene with 1:0.7-1:20 ratio and has 6,000-15,000 wt. av. mol. wt. calcd. as polystyrene. The color filter shows high color d. with .ltoreq.5 .mu.m thickness while providing good color filter characteristics.

IC ICM G03F007-004

ICS G02B005-20

CC 74-13 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)
Section cross-reference(s): 35

ST colored light resin compn color filter CCD camera resin

IT CCD cameras

Light-sensitive materials
Optical filters

(colored light-sensitive resin

compn. for color filters for CCD camera)

IT CCD cameras

Light-sensitive materials
Optical filters

(colored light-sensitive resin

compn. for color filters for CCD camera)

L65 ANSWER 2 OF 15 HCA COPYRIGHT 2005 ACS on STN
140:347504 Negative-working resist compositions containing
acid generator and crosslinker which reacts in the presence of an
acid. Takahashi, Omote; Yasunami, Shoichiro; Shirakawa, Hiroshi
(Fuji Photo Film Co., Ltd., Japan). Jpn. Kokai Tokkyo Koho JP
2004117876 A2 20040415, 61 pp. (Japanese). CODEN: JKXXAF.
APPLICATION: JP 2002-281425 20020926.

GΙ

R12 R11

$$Y^2$$
 R^{14}
 R^{15}
 R^{14}
 R^{15}
 R^{15}
 R^{14}
 R^{15}
 R^{14}
 R^{15}
 R^{15}

The disclosed neg.-working resist compn. contains an alkali-sol. polymer, a crosslinking agent which crosslinks the polymer in the presence of an acid, and a photo-acid generator. The photoacid generator is a compd. of the formula I (Y1, Y2 = alkyl, alkenyl; alkyl group may contain OH or ether bond, Y1 and Y2 may combine to from a ring; R11-15 = H, NO2, halo, alkyl, alkoxy, alkyloxycarbonyl, aryl, acylamino; adjacent two of R11-15 may form a ring; R16, R17 = H, CN, alkyl, aryl; one of R11-15 may combined with one of Y1, Y2, R16, and R17 to form a ring). The crosslinking agent is selected from compd of formula II, III, (R = H, alkyl, acyl; R1-4 = H, OH, alkyl, alkoxy; X = bond, CH2, O) and (ROCH2)2NCON(CH2OR)2

(R is same as in II and III). The **resist** has superior image resoln. and high sensitivity toward x-ray and electron beam, and useful for lithog. fabrication of large-scale integrated circuits.

IT 24979-73-5, 3-Hydroxystyrene-styrene copolymer (photoacid generator type neg. working radiation resist contq.)

RN 24979-73-5 HCA

CN Phenol, 3-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 620-18-8 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

IC ICM G03F007-038 ICS H01L021-027

CC 74-5 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)

ST neg radiation resist acid generator crosslinker; alkoxymethylated melamine crosslinker radiation resist

IT Crosslinking agents

(alkoxymethylated meramines as crosslinkers for acid generation type radiation resists)

IT Electron beam resists

X-ray resists

(crosslinking agents and acid generators for neg.-working)

IT 120976-85-4 454471-15-9 460754-20-5 470482-89-4 474510-73-1 506445-09-6 506445-10-9 506445-12-1 506445-23-4 506445-26-7 506445-28-9 506445-30-3 591244-02-9

(acid generator; photoacid generator type neg. working radiation

resist contq. alcoxymethylated melamine crosslinker and) IT506445-32-5 (acid generator; photoacid generator type neg. working radiation resist contq. alcoxymethylated meramine crosslinker and) IT 679837-88-8 (acid generator; photoacid generator type neg. working radiation resist contq. alkoxymethylated melamine crosslinker and) 5395-50-6, Tetrakis (hydroxymethyl) acetyleneurea IT 3089-11-0 17464-88-9 508220-69-7 625121-00-8 15968-37-3 (crosslinking agent; photoacid generator type neg. working radiation resist contq.) 24979-70-2, Poly(4-hydroxystyrene) **24979-73-5**, IT 3-Hydroxystyrene-styrene copolymer 24979-74-6, 4-Hydroxystyrene-styrene copolymer 149614-53-9, 3-Hydroxystyrene-4-hydroxystyrene copolymer 171429-59-7, 4-Hydroxystyrene-4-vinylphenyl acetate copolymer 185405-14-5, 4-Hydroxystyrene-3,4-methylenedioxystyrene copolymer 204065-67-8, 4-Hydroxystyrene-4-methylstyrene copolymer 219838-71-8, 321164-59-4, 4-Hydroxystyrene-1-Poly(3,5-dihydroxystyrene) 345212-30-8, 3-Hydroxystyrene-3,4,5vinylnaphthalene copolymer trimethoxystyrene copolymer 345212-56-8, 4-Hydroxystyrene-2-345212-59-1, 4-Hydroxystyrene-(5-vinylvinylnaphthalene copolymer 349619-68-7, 3-Hydroxystyrene-4-1-naphthol) copolymer methoxystyrene copolymer 354589-43-8 396098-38-7, 3-Hydroxystyrene-1-vinylnaphthalene copolymer 575464-71-0, 4-Hydroxystyrene-styrene-4-vinylphenyl acetate copolymer (photoacid generator type neg. working radiation resist contq.) ANSWER 3 OF 15 HCA COPYRIGHT 2005 ACS on STN L65

139:108781 Sulfoneamide compounds, their preparation, and their color photopolymer compositions for magenta color filter arrays. Ueda, Yuji; Machiguchi, Kazuhiro; Uchida, Yoshinori; Endo, Hiroki (Sumitomo Chemical Co., Ltd., Japan; Sony Corp.). Jpn. Kokai Tokkyo Koho JP 2003201413 A2 20030718, 11 pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP 2002-3181 20020110.

GI

The sulfoneamide compds., represented by a general formula I (R1 = alkyl, cyclohexylalkyl, alkoxyl, alkoxyalkyl, aryl, aralkyl; R2, R3 = halogen, OH; X = halogen), is prepd. by reacting sulfone halide compds. bearing SO2Y on the naphthalene rings with primary amines R1NH2 (R1 = same as in I) to replace the SO2Y to SO2NHR1. The sulfone halide compds. are prepd. by reacting sulfonyl compds. whose free acids bear SO3H with halogenated thionyl compds. SOY2 (Y = same as above) in the presence of N,N-dialkylformamides to replace the SO3H to SO2NHR1. The color photopolymer compns. contg. I at high concn. are patterned to give magenta color filter layers showing good spectral properties.

IC ICM C09B043-32

ICS C07D239-42; C09B029-28; G02B005-20; G02B005-22

CC 74-13 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)
Section cross-reference(s): 25, 41

ST sulfoneamide compd prepn color filter array; photopolymer compn sulfoneamide magenta color

filter

Phenolic resins, preparation (novolak; prepn. of sulfoneamide compds. and their color photopolymer compns. for magenta color filter arrays)

IT Optical filters

IT

(prepn. of sulfoneamide compds. and their color photopolymer compns. for magenta color filter arrays)

- IT 73817-38-6, Sandolan Milling Red K 4BL
 (C.I. Acid Red 147, Sandolan Milling Red K 4BL; prepn. of
 sulfoneamide compds. and their color photopolymer
 compns. for magenta color filter arrays)
- IT 26505-28-2D, o-naphthoquinonediazide-5-sulfonate derivs. 561054-95-3

(photosensitizer; prepn. of sulfoneamide compds. and their color photopolymer compns. for magenta color filter arrays)

- IT 107-45-9, 1,1,3,3-Tetramethylbutylamine 22374-89-6, 3-Amino-1-phenylbutane 561063-62-5 (prepn. of sulfoneamide compds. and their color photopolymer compns. for magenta color filter arrays)
- IT 68-12-2, N,N-Dimethylformamide, reactions (prepn. of sulfoneamide compds. and their color photopolymer compns. for magenta color filter arrays)
 - IT 68-12-2, N,N-Dimethylformamide, reactions (prepn. of sulfoneamide compds. and their color photopolymer compns. for magenta color filter arrays)
- L65 ANSWER 4 OF 15 HCA COPYRIGHT 2005 ACS on STN
 136:135917 Fabrication of color filter with spacer
 for liquid crystal display. Keitoku, Shiho; Kadono, Tomonobu (Dai
 Nippon Printing Co., Ltd., Japan). Jpn. Kokai Tokkyo Koho JP
 2002031708 A2 20020131, 12 pp. (Japanese). CODEN:
 JKXXAF. APPLICATION: JP 2000-213764 20000714.
- AB Title process comprises (A) formation of a patterned color top of a substrate (e.g., glass), (B) coating of a transcompn. contg. (I) alkali-insol. silicone (e.g., prepdestructure) methacrylate, acrylates, and Si oligomers) and (II) photosensitive resin incompatible to I (e.g., tert-butoxycarbonyl substituted phenolic hydrox; polymer) to form a bilayer structure (I on the bound of the structure) and the structure of the struc

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top), (C) exposure of I via a photomask and development
     with alkali to form spacing columns, and (D) heat treatment to give
     a color filter for liq. crystal display.
ΙT
     72317-19-2P, Hydroxystyrene-styrene copolymer
        (as neg. photoresist in color filter
        fabrication)
RN ·
     72317-19-2 HCA
     Phenol, ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)
CN
     CM
     CRN
          31257-96-2
          C8 H8 O
     CMF
     CCI
          IDS
   D1-OH
D1-CH=CH_2
     CM
     CRN
         100-42-5
     CMF C8 H8
H_2C = CH - Ph
IC
     ICM G02B005-20
          C08L033-04; C08L101-02; G02F001-1335; G02F001-1339;
          G03F007-038; G03F007-039; G03F007-075; G03F007-11; G03F007-40
     38-3 (Plastics Fabrication and Uses)
CC
     Section cross-reference(s): 73, 74
ST
     silicone photoresist spacer color filter
     fabrication liq crystal display
     Polysiloxanes, uses
ΙT
        (acrylic; for fabrication of color filter in
        liq. crystal display)
ΙT
     Phenolic resins, uses
```

(epoxy, novolak; for fabrication of color
filter in liq. crystal display)

IT Liquid crystal displays

(fabrication of **color filter** with spacing column for)

IT Negative photoresists

Positive photoresists

(for fabrication of color filter in liq. crystal display)

IT Phase separation

(for fabrication of color filter with spacing column in liq. crystal display)

IT Epoxy resins, uses

(phenolic, novolak; for fabrication of color filter in liq. crystal display)

IT Acrylic polymers, uses

(polysiloxane-; for fabrication of color filter in liq. crystal display)

IT Optical filters

(with spacing column fabricated for liq. crystal display)

IT 71868-10-5, Irgacure 907 85342-62-7, NAI 105 (as modifier for fabrication of color filter in liq. crystal display)

IT 100-42-5D, Styrene, polymers, tert-butoxycarbonyl substituted (contg. phenolic hydroxyl group as pos. photoresist in color filter fabrication)

IT 80-62-6DP, Methyl methacrylate, polymers with acrylates and Si oligomers 4074-88-8DP, Diethylene glycol diacrylate, polymers with acrylates and Si oligomers

(for fabrication of color filter in liq. crystal display)

L65 ANSWER 5 OF 15 HCA COPYRIGHT 2005 ACS on STN

130:345146 Manufacture of color filter using positive-working photosensitive colored composition. Suzuki, Nobuo (Fuji Photo Film Co., Ltd., Japan). Jpn. Kokai Tokkyo Koho JP 11119017 A2 19990430 Heisei, 62 pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP 1997-282267 19971015.

AB Color filter is manufd. by coating a transparent substrate with title compn. contg. (1) a resin insol. in water and sol. in an alk. aq. soln., (2) a compd. generating acid upon active ray or radiation irradn., (3) a compd. of mol. wt. .ltoreq.3000 having a group that is decompd. by acid to increase soly. in an alk. developing soln., and (4) a colorant, light exposure, heating, developing, adding a crosslinking agent, light

IT

RN

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exposure, and heating. Alternatively, the compn. contains (1) a
     resin having a group that is decompd. by acid to increase soly. in
     an alk. developing soln., (2) a compd. generating acid by active ray
     or radiation irradn., (3) an org. basic compd., and (4) a colorant.
     The filter is useful for liq. crystal displays and
     solid-state image pickup devices and shows heat and chem.
     resistance, high sensitivity, and good pattern profile and colorant
     dispersibility.
     24979-74-6, 4-Hydroxystyrene-styrene copolymer
        (alkali-sol. resin; color filter using
        pos.-working photosensitive colored resin compn.)
     24979-74-6 HCA
     Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX
     NAME)
     CM
          1
     CRN
          2628-17-3
     CMF
          C8 H8 O
           CH=CH2
     CM
          2
     CRN
          100-42-5
     CMF
          C8 H8
H_2C = CH - Ph
         G02B005-20
     ICM
          C09D007-12; C09D201-00; G03F007-004; G03F007-40
     74-13 (Radiation Chemistry, Photochemistry, and Photographic and
     Other Reprographic Processes)
     color filter pos working photosensitive
     resin; acid decomposable dissoln inhibitor color
     filter; liq crystal display color filter
     ; image pickup device color filter
     Liquid crystal displays
     Optical filters
     Optical imaging devices
        (color filter using pos.-working
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photosensitive colored resin compn.)

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ΙT
     Photoimaging materials
        (color; color filter using
        pos.-working photosensitive colored resin compn.)
IT
     Aminoplasts
        (crosslinking agent; color filter using
        pos.-working photosensitive colored resin compn.)
                  66003-78-9, Triphenylsulfonium
IT
     56530-39-3
                                 124737-97-9
     trifluoromethanesulfonate
        (acid generator; color filter using
        pos.-working photosensitive colored resin compn.)
IT
     142952-62-3
                   180337-31-9 196709-91-8
        (acid-decomposable resin; color filter using
        pos.-working photosensitive colored resin compn.)
IT
     24979-74-6, 4-Hydroxystyrene-styrene copolymer
        (alkali-sol. resin; color filter using
        pos.-working photosensitive colored resin compn.)
     101-80-4, 4,4'-Diaminodiphenyl ether 484-47-9,
IT
     2,4,5-Triphenylimidazole 1122-58-3, 4-Dimethylaminopyridine
        (base; color filter using pos.-working
        photosensitive colored resin compn.)
IT
     9003-08-1, Formaldehyde-melamine copolymer
        (crosslinking agent; color filter using
        pos.-working photosensitive colored resin compn.)
ΙT
     153698-54-5
                   153698-63-6
                                 186493-32-3
        (dissoln. inhibitor; color filter using
        pos.-working photosensitive colored resin compn.)
     147-14-8, C.I.Pigment Blue 15:6 4051-63-2, C.I.Pigment Red 177
ΙT
     14302-13-7, C.I.Pigment Green 36 36888-99-0, C.I.Pigment Yellow
     139
        (pigment; color filter using pos.-working
        photosensitive colored resin compn.)
     ANSWER 6 OF 15 HCA COPYRIGHT 2005 ACS on STN
130:304048 Positively-working photosensitive colored
     composition and color filter using same.
     Suzuki, Nobuo (Fuji Photo Film Co., Ltd., Japan). Jpn. Kokai Tokkyo
     Koho JP 11095435 A2 19990409 Heisei, 62 pp. (Japanese).
     CODEN: JKXXAF. APPLICATION: JP 1997-252177 19970917.
AB
     The title compn. contains (a) a resin insol. in water and sol. in
     aq. alk. solns., (b) a compd. generating acid under active ray or
     radiation irradn., (c) a low-mol.-wt. acid-decomposable
     dissoln.-inhibiting compd. with mol. wt. .ltoreq.3000 which has
     acid-decomposable groups whose soly. in alk. developing solns. is
     increased by the action of acid, and (d) a colorant. The compn. may
     contain (a) a resin having groups which are decompd. by the action
     of acid to increase the soly. in alk. developing solns., (b) a
     compd. generating acid under active ray or radiation irradn., (c) an
     org. basic compd., and (d) a colorant. A color
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filter using the compn. is also claimed. The compn. shows high photosensitivity and provides high quality patterns with good profile.

IT 24979-74-6, p-Hydroxystyrene-styrene copolymer (pos. working photoresist material contg. alkali-sol. resin or acid-decomposable resin for manuf. of color filter)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C \longrightarrow CH - Ph$

IC ICM G03F007-039

ICS C08L101-00; C09D201-00; G02B005-20; G03F007-004

CC 74-5 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)

pos working photosensitive compn color filter; acid decompn inhibitor pos working photoresist; alkali soly acid decomposable compn

IT Optical filters

Positive photoresists

(pos. working **photoresist** material contg. alkali-sol. resin or acid-decomposable resin for manuf. of **color filter**)

IT 153698-54-5 153698-63-6 186493-32-3

(acid decompn. inhibitor; in pos. working **photoresist** material contg. alkali-sol. resin or acid-decomposable resin for manuf. of **color filter**)

IT 56530-39-3 66003-78-9 124737-97-9

(acid generator; in pos. working **photoresist** material contg. alkali-sol. resin or acid-decomposable resin for manuf. of **color filter**)

IT 101-80-4 484-47-9 1122-58-3

(in pos. working photoresist material contg.

alkali-sol. resin or acid-decomposable resin for manuf. of color filter)

IT **24979-74-6,** p-Hydroxystyrene-styrene copolymer 142952-62-3 180337-31-9 196709-91-8 223473-73-2

(pos. working **photoresist** material contg. alkali-sol. resin or acid-decomposable resin for manuf. of **color filter**)

L65 ANSWER 7 OF 15 HCA COPYRIGHT 2005 ACS on STN;

128:161006 Negative-working radiation-sensitive resin composition useful as resist. Iwanaga, Shinichiro; Ikesaki, Yoji; Ota, Yoshiji; Tanabe, Takaki (Japan Synthetic Rubber Co., Ltd., Japan). Jpn. Kokai Tokkyo Koho JP 10010733 A2 19980116 Heisei, 9 pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP 1996-178670 19960620.

AB The title compn. comprises an alkala-sol. resin contg. .gtoreq.1 selected from hydroxystyrene-styrene copolymers and hydroxystyrene-alpha.-methylstyrene copolymer in which the hydroxystyrene unit content is 70-95 mol%, a radiation-sensitive acid-generating agent, and a crosslinking agent. The compn. shows high photosensitivity, developability, and dimensional stability and provides high resoln. patterns with good profile. Thus, a resist comprised p-hydroxystyrene-styrene copolymer, tris(2,3-dibromopropyl) isocyanurate, and methoxymethylated urea resin.

IT 24979-73-5 24979-75-7

(radiation-sensitive resist compn. contg. hydroxystyrene-(methyl) styrene copolymer)

RN 24979-73-5 HCA

CN Phenol, 3-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 620-18-8 CMF C8 H8 O

CM

2

```
100-42-5
     CRN
     CMF
          C8 H8
H_2C = CH - Ph
RN
     24979-75-7 HCA
     Phenol, 2-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX
CN
     NAME)
     CM
          1
     CRN
          695-84-1
     CMF
          C8 H8 O
       CH = CH_2
       OH
     CM
          2
          100-42-5
     CRN
     CMF
          C8 H8
H_2C = CH - Ph
IC
     ICM G03F007-038
          G03F007-004; G03F007-033; H01L021-027
     74-5 (Radiation Chemistry, Photochemistry, and Photographic and
CC
     Other Reprographic Processes)
     Section cross-reference(s): 38
     hydroxystyrene styrene copolymer radiation sensitive resist
ST
     ; methylstyrene hydroxystyrene copolymer radiation sensitive
     resist
IT
     Aminoplasts
        (radiation-sensitive resist compn. contg.
        hydroxystyrene-(methyl)styrene copolymer)
ΙT
     Resists
        (radiation-sensitive, neg.-working; radiation-sensitive
        resist compn. contg. hydroxystyrene-(methyl)styrene
        copolymer)
```

- IT 9003-08-1, Melamine resin 9011-05-6, Urea resin 24979-73-5
 24979-74-6, p-Hydroxystyrene-styrene copolymer 24979-75-7
 127523-21-1, p-Hydroxystyrene-.alpha.-methylstyrene copolymer
 (radiation-sensitive resist compn. contg.
 hydroxystyrene-(methyl)styrene copolymer)
- L65 ANSWER 8 OF 15 HCA COPYRIGHT 2005 ACS on STN
- 128:121746 Negative-working radiation-sensitive resin composition useful as chemical amplification-type resist. Iwanaga, Shinichiro; Ikezaki, Yoji; Ota, Yoshihisa; Tanabe, Takayoshi (Japan Synthetic Rubber Co., Ltd., Japan). Jpn. Kokai Tokkyo Koho JP 09325495 A2 19971216 Heisei, 9 pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP 1996-165089 19960606.
- The title compn. contains an alkali-sol. resin, a radiation-sensitive acid-generating agent, and a compd. R10(R2O)nCH2NHCONHCH2(OR3)mOR4 [R1, R4 = H, C1-4 (halogenated) alkyl which may be branched; R2, R3 = CH2, C2-4 alkylene, C2-4 alkylidene; n, m = 1-5] as a crosslinking agent. The compn. shows improved developability and high photosensitivity and provides high resoln. patterns with good profile and dimensional stability.
- IC ICM G03F007-038 ICS G03F007-004; H01L021-027
- CC 74-5 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)
 Section cross-reference(s): 37
- ST neg working radiation resist alkoxy urea
- IT Resists

(neg.-working radiation-sensitive; radiation-sensitive
resist compn. contg. urea compd. crosslinking agent)

- IT 201683-94-5P 201683-95-6P 201683-96-7P 201683-97-8P (radiation-sensitive resist compn. contg. urea compd. crosslinking agent)
- L65 ANSWER 9 OF 15 HCA COPYRIGHT 2005 ACS on STN

 127:301259 Method of forming positive resist pattern with
 excellent shape retention. Yamamoto, Shigeki; Nogita, Tsuyuko
 (Sumitomo Chemical Co., Ltd., Japan). Jpn. Kokai Tokkyo Koho JP
 09230608 A2 19970905 Heisei, 7 pp. (Japanese). CODEN:
 JKXXAF. APPLICATION: JP 1996-609 19960108. PRIORITY: JP
 1995-334556 19951222.
- AB The process comprises the steps of: (1) coating a substrate with a pos.-type resist compn. consisting of a solvent, a quinonediazide compd., and a compd. contq. sulfonyl amide,

carboxylic amide, and/or ureido groups, in which any one of Hs is replaced by a group; (2) exposing through a mask; (3) developing to remove the exposed area, thereby forming a pos.-type pattern; and (4) hardening the pattern by heating. The quinonediazide compd. may be 1,2-naphthoquinonediazidesulfonyl ester. The process is used in manufg. semiconductor materials, printing plates, color filters, and the like. The process provided the resist pattern having excellent properties such as solvent fastness, adhesivity with a substrate, etching resistance, and heat resistance.

- IC ICM G03F007-40
 - ICS G03F007-022; G03F007-023; H01L021-027
- CC 74-5 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)
 Section cross-reference(s): 76
- ST pos resist pattern shape retention; printing plate pos resist pattern; semiconductor device pos resist pattern
- IT Printing plates
 Semiconductor devices

(method of forming pos. resist pattern with excellent shape retention)

IT Photoresists

(prepn. of sulfonamide dye for formation of pos. resist pattern)

- IT Dves
 - (sulfonamide deriv.; prepn. of sulfonamide dye for formation of pos. resist pattern)
- 17 1934-21-0D, reaction product with thionyl chloride and 3-(2-ethylhexyloxy)propylamine 6375-55-9D, reaction product with thionyl chloride and 3-(2-ethylhexyloxy)propylamine 7719-09-7D, Thionyl chloride, reaction product with (1) (shown in p. 5) and 3-(2-ethylhexyloxy)propylamine 22374-89-6D, reaction product with (1) (shown in p. 5) and thionyl chloride 197020-33-0D, reaction product with (1) (shown in p. 5) and thionyl chloride (prepn. of sulfonamide dye for formation of pos. resist pattern)
- IT 3770-97-6DP, 1,2-Naphthoquinonediazide-5-sulfonylchloride, ester
 with 4-(1',2',3',4',4'a, 9'a-hexahydro-6'-hydroxy5'methylspiro[cyclohexane-1,9'xanthene]-4'a-yl)-2-methylresolcinol
 27029-76-1P, m-Cresol-p-cresol-formaldehyde copolymer 108388-54-1P
 159339-70-5DP, ester with 1,2-naphthoquinonediazide-5sulfonylchlorided

(prepn. of sulfonamide dye for formation of pos. resist pattern)

IT 3770-97-6DP, 1,2-Naphthoquinonediazide-5-sulfonylchloride, ester with 4-(1',2',3',4',4'a, 9'a-hexahydro-6'-hydroxy-5'methylspiro[cyclohexane-1,9'xanthene]-4'a-yl)-2-methylresolcinol

27029-76-1P, m-Cresol-p-cresol-formaldehyde copolymer 108388-54-1P 159339-70-5DP, ester with 1,2-naphthoquinonediazide-5-sulfonylchlorided

(prepn. of sulfonamide dye for formation of pos. resist pattern)

L65 ANSWER 10 OF 15 HCA COPYRIGHT 2005 ACS on STN

124:234022 Compositions for color filters and microlens arrays, and color filters and microlens arrays therefrom, manufacture thereof. Hishiro, Yoshiki; Yamamoto, Shigeki; Takeyama, Naomiki (Sumitomo Chemical Co., Ltd., Japan). Jpn. Kokai Tokkyo Koho JP 07306309 A2 19951121 Heisei, 12 pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP 1994-97748 19940511.

GΙ

$$T^2$$
 Z^1
 Z^2
 Z^3
 Z^4
 Z^5
 Z^4
 Z^5
 Z^5
 Z^5
 Z^5
 Z^7
 Z^7

The title compns. for color color

filters for solid imaging devices with excellent color

reprodn., color d. and heat resistance contain alkali-sol. resins

prepd. from phenols I and II (Z1 = 0, direct bond; Z2, Z3 = alkyl,

hydroxyphenyl, excluding Z1 = Z2; Z4-6 = alkyl; T1, T2 = H, OH; U1,

U2 = H, alkyl) in the presence of an acid catalyst. A compn. from

hexakis(methoxymethyl)melamine 0.2, novolak [m-cresol, p-cresol,

HCHO, and 2-(2,4-dihydroxyphenyl)-7-hydroxy-2,4,4-trimethyl-2H
benzopyran in 5:5:7.5:5 molar ratio, Mw 3000] 1,

2,6-bis(2,5-dimethyl-4-hydroxybenzyl)-4-methylphenol

bis(o-naphthoquinonediazide-5-sulfonate) 0.8, and Et lactate 0.5

parts was used for patterning, exposed, and heated for flow and

curing to form lenses with excellent heat resistance.

IT **24979-74-6**, Maruka Lyncur CST-70

(compns. for color filters and microlens arrays, and color filters and microlens arrays therefrom, manuf. thereof)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI)

```
NAME)
     CM
          1
     CRN
          2628-17-3
     CMF C8 H8 O
           CH=CH2
     CM
          2
          100-42-5
     CRN
          C8 H8
     CMF
H_2C = CH - Ph
IC
     ICM G02B005-20
          C08L061-06; G02B003-00; G03F007-004; G03F007-023; G03F007-26
     37-6 (Plastics Manufacture and Processing)
CC
     Section cross-reference(s): 74, 76
ST
     heat resistant microlens array imaging; solid imaging device
     color filter; phenolic resin microlens
     color filter
ΙT
    Heat-resistant materials
     Lenses
    Optical filters
     Optical imaging devices
        (compns. for color filters and microlens
        arrays, and color filters and microlens
        arrays therefrom, manuf. thereof)
IT
     Phenolic resins, preparation
        (compns. for color filters and microlens
        arrays, and color filters and microlens
        arrays therefrom, manuf. thereof)
                154778-51-5
ΙT
     3584-23-4
                              155643-84-8
                                             160778-56-3
                                                            173692-95-0
        (compns. for color filters and microlens
        arrays, and color filters and microlens
        arrays therefrom, manuf. thereof)
     108388-54-1P
                                   173419-88-0P
ΙT
                    173419-87-9P
                                                  173419-89-1P
     173419-90-4P
                    173419-91-5P
                                   173419-93-7P
        (compns. for color filters and microlens
```

arrays, and color filters and microlens

arrays therefrom, manuf. thereof)

IT 24979-74-6, Maruka Lyncur CST-70 25085-34-1, Acrylic acid-styrene copolymer

(compns. for color filters and microlens arrays, and color filters and microlens arrays therefrom, manuf. thereof)

IT 6375-55-9, Suminol Milling Yellow MR 173419-92-6 (compns. for color filters and microlens arrays, and color filters and microlens arrays therefrom, manuf. thereof)

IT 6375-55-9, Suminol Milling Yellow MR 173419-92-6 (compns. for color filters and microlens arrays, and color filters and microlens arrays therefrom, manuf. thereof)

L65 ANSWER 11 OF 15 HCA COPYRIGHT 2005 ACS on STN

122:57472 Photosensitive novolak resin composition for color filter. Hishiro, Yoshiki; Takeyama, Naoki; Yamamoto, Shigeki (Sumitomo Chemical Co., Ltd., Japan). PCT Int. Appl. WO 9414892 A1 19940707, 39 pp. DESIGNATED STATES:

W: JP, KR, US; RW: AT, BE, CH, DE, DK, ES, FR, GB, GR, IE, IT, LU, MC, NL, PT, SE. (Japanese). CODEN: PIXXD2. APPLICATION: WO 1993-JP1872 19931224. PRIORITY: JP 1992-344337 19921224; JP 1992-344336 19921224; JP 1993-17694 19930204; JP 1993-17693 19930204.

AB The title compn., with good resoln., heat resistance (no change at 200.degree. for 40 min), and transparency, comprises a novolak resin contg. specific repeating units and having mol. wt. 1000-50,000 (e.g., copolymer of formaldehyde and reaction products of m-isopropenylphenol and BF3-di-Et ether complex in toluene), a solvent, and a dye or pigment (e.g., Oleosol Fast Blue RL).

IT 24979-74-6, Maruka Lyncur CST 70 (photosensitive novolak resin compn. for color filter)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM

2

```
CRN
          100-42-5
     CMF
          C8 H8
H_2C = CH - Ph
IC
     ICM
         C08L061-06
     ICS
          G03F007-023; G02B005-20
     37-6 (Plastics Manufacture and Processing)
CC
     Section cross-reference(s): 73
ST
     photosensitive novolak compn color
     filter; resoln novolak compn color filter
     ; heat resistance novolak color filter;
     transparency novolak compn color filter
IT .
     Dyes
     Heat-resistant materials
     Optical filters
     Pigments
        (photosensitive novolak resin compn. for color
        filter)
     Phenolic resins, uses
IT
        (novolak, photosensitive novolak resin compn. for
        color filter)
ΙT
     3584-23-4
                 20546-03-6 24979-71-3, Maruka Lyncur CMM
     24979-74-6, Maruka Lyncur CST 70
                                        159339-70-5
     160170-91-2, Maruka Lyncur PHS-C
                                        160171-00-6, Oleosol Fast Blue RL
        (photosensitive novolak resin compn. for color
        filter)
                   159949-28-7
     108388-54-1
IT
        (photosensitive novolak resin compn. for color
        filter)
     ANSWER 12 OF 15 HCA COPYRIGHT 2005 ACS on STN
122:42778 Resist compositions for color
     filters. Hishiro, Yoshiki; Takeyama, Naomiki; Yamamoto,
     Shigeki (Sumitomo Chemical Co., Ltd., Japan). Jpn. Kokai Tokkyo
     Koho JP 06194835 A2 19940715 Heisei, 7 pp. (Japanese).
     CODEN: JKXXAF. APPLICATION: JP 1992-344338 19921224.
     The title resist compns. contain an alkali-sol. novolak
AB
     resin, .gtoreq.1 alkali-sol. vinyl polymer, a solvent, and a dye.
     color filter prepd. from a resist compn.
     comprising m-cresol-p-cresol-HCHO novolak resin, Marukalyncur-CST-70
     (vinylphenol resin), a quinonediazide compd., a crosslinking agent,
     Et lactate, and Oleosol Fast Blue RL (dye) had a high resoln.
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```
pattern with good thermal resistance.
     24979-74-6, Marukalyncur CST 70
IT
        (photoresists compns. contq. alkali-sol. novolak
     resins, polyvinyls, and dyes for color filters
RN
     24979-74-6 HCA
     Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX
CN
     NAME)
     CM
     CRN 2628-17-3
     CMF
          C8 H8 O
           CH=CH2
     CM
          100-42-5
     CRN
          C8 H8
     CMF
H_2C = CH - Ph
IC
     ICM G03F007-038
     ICS G03F007-004; G03F007-022; G03F007-039
ICA
    G02B005-20
     74-5 (Radiation Chemistry, Photochemistry, and Photographic and
CC
     Other Reprographic Processes)
     color filter resist novolak resin;
ST
     alkali sol polyvinyl dye resist
     Crosslinking agents
IT
     Optical filters
        (photoresists compns. contg. alkali-sol. novolak
        resins, polyvinyls, and dyes for color filters
ΙT
     Phenolic resins, uses
        (novolak, photoresists compns. contg. alkali-sol.
        novolak resins, polyvinyls, and dyes for color
        filters)
IT
    Resists
        (photo-, photoresists compns. contg. alkali-sol.
        novolak resins, polyvinyls, and dyes for color
```

```
filters)
ΙT
     3584-23-4
        (acid generator; photoresists compns. contg.
        alkali-sol. novolak resins, polyvinyls, and dyes for
        color filters)
ΙT
     9003-08-1, Melamine resin
        (crosslinking agents, hexamethoxymethylol group-contg.;
        photoresists compns. contg. alkali-sol. novolak resins,
        polyvinyls, and dyes for color filters)
ΙT
     53252-02-1D, esters
        (photoresists compns. contg. alkali-sol. novolak
        resins, polyvinyls, and dyes for color filters
     12237-22-8, C.I. Solvent Black 27
                                         24979-70-2
IT
                                                      24979-71-3,
     Marukalyncur CMM 24979-74-6, Marukalyncur CST 70
     27029-76-1, m-Cresol-p-cresol-formaldehyde copolymer
                                                            59269-51-1,
     Poly(vinylphenol)
        (photoresists compns. contq. alkali-sol. novolak
        resins, polyvinyls, and dyes for color filters
L65 ANSWER 13 OF 15 HCA COPYRIGHT 2005 ACS on STN
122:42777 Resist compositions for color
     filters. Hishiro, Yoshiki; Takeyama, Naomiki; Yamamoto,
     Shigeki (Sumitomo Chemical Co., Ltd., Japan). Jpn. Kokai Tokkyo
     Koho JP 06194828 A2 19940715 Heisei, 7 pp. (Japanese).
     CODEN: JKXXAF. APPLICATION: JP 1992-344340 19921224.
     The title resist compns. contain an acidic dye amine salt
AB
     or an acidic dye sulfonamide compd. as an org. solvent- and alk. ag.
     soln.-sol. dye and an alkali-sol. vinyl polymer. A color
     filter prepd. from a resist compn. comprising
     Marukalyncur-M [poly(vinylphenol)], a sulfonamide deriv. (prepd.
     from Cu phthalocyaninesulfonyl chloride and dodecylamine), and a
     quinonediazide compd. had a stable colored pattern with high resoln.
     24979-74-6, Marukalyncur CST 70
ΙT
        (photoresists compns. contg. alkali-sol. acidic dye
        derivs. and and polyvinyls for color filters)
     24979-74-6 HCA
RN
CN
     Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX
     NAME)
     CM
     CRN
          2628-17-3
     CMF C8 H8 O
```

$$CH = CH_2$$
 $CM = 2$

H2C= CH- Ph

CRN

CMF

IC ICM G03F007-022 ICS C09B047-04; G03F007-004

100-42-5

C8 H8

ICA G02B005-20

CC 74-5 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)

ST color filter resist acidic dye; polyvinyl acidic dye resist

IT Optical filters

(photoresists compns. contg. alkali-sol. acidic dye derivs. and and polyvinyls for color filters)

IT Resists

(photo-, photoresists compns. contg. alkali-sol. acidic dye derivs. and and polyvinyls for color filters)

IT 24979-70-2, Poly(vinylphenyl)

(Marukalyncur M; photoresists compns. contg. alkali-sol. acidic dye derivs. and and polyvinyls for color filters)

IT 9003-08-1, Melamine resin

(crosslinking agents, hexamethoxymethylol group-contg.; photoresists compns. contg. alkali-sol. acidic dye derivs. and and polyvinyls for color filters)

IT 53252-02-1D, o-Naphthoquinone diazide 5-sulfonic acid, esters (photoresists compns. contg. alkali-sol. acidic dye derivs. and and polyvinyls for color filters)

124-22-1DP, Dodecylamine, reaction products with acidic dye 7617-78-9DP, 3-Decyloxypropylamine, reaction products with acidic dye 27360-85-6DP, C.I. Acid Blue 249, reaction products with amines

(photoresists compns. contg. alkali-sol. acidic dye derivs. and and polyvinyls for color filters)

IT 24979-74-6, Marukalyncur CST 70 157480-50-7D, Aminol Fast

Brilliant Pink RL, reaction products with amine (photoresists compns. contg. alkali-sol. acidic dye derivs. and and polyvinyls for color filters)

L65 ANSWER 14 OF 15 HCA COPYRIGHT 2005 ACS on STN

122:42776 Resist compositions for color

filters. Hishiro, Yoshiki; Takeyama, Naomiki; Yamamoto, Shigeki (Sumitomo Chemical Co., Ltd., Japan). Jpn. Kokai Tokkyo Koho JP 06194827 A2 19940715 Heisei, 7 pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP 1992-344339 19921224.

The title resist compns. contain an alkali-sol. novolak resin, .gtoreq.1 alkali-sol. vinyl polymer, a solvent, and a pigment. A color filter prepd. from a resist compn. comprising m-cresol-p-cresol-HCHO novolak resin, Marukalyncur-CST-70 (vinyl polymer), a quinonediazide compd., hexamethoxymethylol group contg.-melamine resin, Et cellosolve acetate, C.I. Pigment Blue 15, and C.I. Pigment Violet 23 had a high resoln. pattern with good thermal resistance.

IT **24979-74-6**, Marukalyncur CST 70

(photoresists compns. contg. alkali-sol. novolak resins, polyvinyls, and pigments for color filters)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

IC ICM G03F007-022 ICA G02B005-20

- CC 74-5 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes) ST color filter resist novolak resin; alkali sol polyvinyl pigment resist ΙT Crosslinking agents Optical filters (photoresists compns. contg. alkali-sol. novolak resins, polyvinyls, and pigments for color filters) ΙT Phenolic resins, uses (novolak, photoresists compns. contg. alkali-sol. novolak resins, polyvinyls, and pigments for color filters) ΙT Resists (photo-, photoresists compns. contg. alkali-sol. novolak resins, polyvinyls, and pigments for color filters) 3584-23-4 IT (acid generator; photoresists compns. contg. alkali-sol. novolak resins, polyvinyls, and pigments for color filters) 9003-08-1, Melamine resin IT (crosslinking agents, hexamethoxymethylol group-contg.; photoresists compns. contg. alkali-sol. novolak resins, polyvinyls, and pigments for color filters) ΙT 53252-02-1D, Naphthoquinone diazide 5-sulfonic acid, esters (photoresists compns. contg. alkali-sol. novolak resins, polyvinyls, and pigments for color filters) 147-14-8, C.I. Pigment Blue 15 6358-30-1, C.I. Pigment Violet 23 IT 24979-71-3, Marukalyncur CMM **24979-74-6**, Marukalyncur CST 27029-76-1, m-Cresol-p-cresol-formaldehyde copolymer 59269-51-1, Poly(vinylphenol) 160170-91-2, Maruka Lyncur PHS-C (photoresists compns. contg. alkali-sol. novolak resins, polyvinyls, and pigments for color filters) ANSWER 15 OF 15 HCA COPYRIGHT 2005 ACS on STN 117:140829 Photosensitive colored resin composition, colored image formation method of color filter, and formation method of black matrix. Kurata, Nobuyuki; Ishii, Keiji; Kikuchi, Hideo; Hayashi, Keiichi (Toyo Gosei Kogyo Co., Ltd., Japan). Eur. Pat. Appl. EP_483693 A2 19920506, 13 pp. DESIGNATED STATES: R: DE, NL. (English). CODEN: EPXXDW. APPLICATION: EP 1991-118267 19911025. PRIORITY: JP 1990-288504 19901029; JP 1990-303763 19901113; JP 1990-303764 19901113.
- AB A photosensitive colored resin compn. for the formation of colored images includes (a) a resin-based material hardenable with

an acid, (b) a photoreactive acid-releasing agent, and (c) a pigment. A colored image formation method of a color filter suitable for a liq.-crystal display panel includes (1) coating a photosensitive colored resin compn. on a transparent substrate and drying the coating to form a colored resin layer, (2) pattern exposing, (3) heating, and (4) developing the exposed and heated colored resin layer with an alk. developing soln. to form a colored image on the transparent substrate. The steps are repeated to form a multicolored image on the same substrate. formation method of a black matrix for the formation of a color filter is also described. 24979-74-6 (photosensitive compns. contg., for prodn. of optical filters) 24979-74-6 HCA Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME) CM 1 CRN 2628-17-3 CMF C8 H8 O $CH = CH_2$ CM 2 100-42-5 CRN CMF C8 H8 $H_2C = CH - Ph$ ICM G03F007-039 G03C007-12; G03F007-022 ICS 74-13 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes) color filter liq crystal display; photoimaging compn optical filter Optical filters (photosensitive compns. for prodn. of)

ΙT

RN

CN

IC

CC

ST

IT

IT

Optical imaging devices

(electro-, liq.-crystal, color filter prodn.)

```
ΙT
     Phenolic resins, uses
        (novolak, photosensitive compns. contg., for prodn. of
        optical filters)
                 1675-54-3, Bisphenol A diglycidyl ether
ΙT
     1042-84-8
                                                           3584-23-4
     9003-08-1, Cymel 300 9016-83-5, Cresol-formaldehyde copolymer
     24979-71-3 24979-74-6
                             59269-51-1, Polyvinylphenol
     63226-13-1
                  66003-76-7
                               66810-89-7, Cymel 1123
                                                        69432-40-2
     106870-13-7
                   115168-59-7
        (photosensitive compns. contg., for prodn. of optical
        filters)
=> d his 166-
     FILE 'HCA' ENTERED AT 18:36:03 ON 10 FEB 2005
L66
             76 S L6/D OR L6/DP
L67
             81 S L34/D OR L34/DP
             13 S L47/D OR L47/DP
L68
L69
             39 S L64 NOT (L66 OR L67 OR L68)
=> d 169 1-39 cbib fhitstr
     ANSWER 1 OF 39 HCA COPYRIGHT 2005 ACS on STN
137:39321 Positively working resist composition containing
     fluoropolymer for high resolution. Adegawa, Yutaka; Tan, Shiro;
     Sorori, Tadahiro (Fuji Photo Film Co., Ltd., Japan). Jpn. Kokai
     Tokkyo Koho JP 2002169295 A2 20020614, 124 pp.
     (Japanese). CODEN: JKXXAF. APPLICATION: JP 2001-272097 20010907.
     PRIORITY: JP 2000-276896 20000912; JP 2000-283963 20000919.
ΙT
     24979-74-6P, p-Hydroxystyrene-styrene copolymer
        (pos. working resist compn. contg. fluoropolymer for
        high resoln.)
RN
     24979-74-6 HCA
     Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX
CN
     NAME)
     CM
          1
     CRN
          2628-17-3
     CMF C8 H8 O
```

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 2 OF 39 HCA COPYRIGHT 2005 ACS on STN

136:348304 Positive photosensitive composition. Kodama,
Kunihiko; Aoai, Toshiaki (Fuji Photo Film Co., Ltd., Japan). Eur.
Pat. Appl. EP 1199603 A1 20020424, 148 pp. DESIGNATED
STATES: R: AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE,
MC, PT, IE, SI, LT, LV, FI, RO, MK, CY, AL, TR. (English). CODEN:
EPXXDW. APPLICATION: EP 2001-124329 20011019. PRIORITY: JP
2000-321128 20001020; JP 2000-352899 20001120; JP 2001-132546
20010427.

IT 24979-74-6, p-Hydroxystyrene-styrene copolymer (photo-acid generator used in pos. photoresist compn.)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8 $H_2C = CH - Ph$

L69 ANSWER 3 OF 39 HCA COPYRIGHT 2005 ACS on STN

135:378752 Chemically amplified negatively working radiation-sensitive resin composition. Kai, Toshiyuki; Ota, Yoshihisa; Ichinohe, Daigo (JSR Ltd., Japan). Jpn. Kokai Tokkyo Koho JP 2001324811 A2 20011122, 22 pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP 2000-142750 20000516.

IT 24979-74-6, Styrene-p-vinylphenol copolymer (chem. amplified neg. working radiation-sensitive resin compn.)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 4 OF 39 HCA COPYRIGHT 2005 ACS on STN

135:68564 Negative radiation-sensitive chemically amplified resin composition. Kai, Toshiyuki; Wang, Yong; Kusumoto, Shirou; Ohta, Yoshihisa (Jsr Corp., Japan). Eur. Pat. Appl. EP 1111465 A1 20010627, 15 pp. DESIGNATED STATES: R: AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT, IE, SI, LT, LV, FI, RO. (English). CODEN: EPXXDW. APPLICATION: EP 2000-128363 20001222. PRIORITY: JP 1999-367575 19991224.

IT 24979-74-6, p-Hydroxystyrene-styrene copolymer (neg. radiation-sensitive chem. amplified resin compn.

comprising)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 5 OF 39 HCA COPYRIGHT 2005 ACS on STN
134:23501 Sulfonic acid onium salt and radiation-sensitive resin composition using same. Wang, Isamu; Kobayashi, Eiichi (JSR Co., Ltd., Japan). Jpn. Kokai Tokkyo Koho JP 2000327654 A2
20001128, 34 pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP 1999-135030 19990514.

L69 ANSWER 6 OF 39 HCA COPYRIGHT 2005 ACS on STN
133:274235 Radiation sensitive positive-working resist resin
composition. Tan, Shiro; Aogo, Toshiaki; Fujiomori, Toru (Fuji
Photo Film Co., Ltd., Japan). Jpn. Kokai Tokkyo Koho JP 2000258913
A2 20000922, 33 pp. (Japanese). CODEN: JKXXAF.
APPLICATION: JP 1999-60286 19990308.

IT 24979-74-6P, p-Hydroxystyrene-styrene copolymer (polymer in radiation-sensitive pos.-working resist resin compn.)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 7 OF 39 HCA COPYRIGHT 2005 ACS on STN

131:80784 Positive-working photoresist composition containing two kinds of photoacid generator. Uenishi, Kazuya; Kodama, Kunihiko; Aogo, Toshiaki; Sato, Kenichiro (Fuji Photo Film Co., Ltd., Japan). Jpn. Kokai Tokkyo Koho JP 11167199 A2 19990622 Heisei, 57 pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP 1997-333145 19971203.

IT 24979-74-6, p-Hydroxystyrene-styrene copolymer (dissoln. inhibitor; photoresist compn. contg. alkali sol. resin and two kinds of photoacid generator)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5

CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 8 OF 39 HCA COPYRIGHT 2005 ACS on STN

130:330572 Radiation-sensitive resin composition useful as chemically amplified **resist**. Ohta, Yoshihisa; Matsuda, Daiichi; Yumoto, Yoshitsugu (JSR Co., Ltd., Japan). Jpn. Kokai Tokkyo Koho JP 11109613 A2 19990423 Heisei, 21 pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP 1997-281078 19970930.

IT 24979-74-6, p-Hydroxystyrene-styrene copolymer (resist compn. contg. fullerene deriv.)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 9 OF 39 HCA COPYRIGHT 2005 ACS on STN

130:175297 Radiation-sensitive resin compositions. Kobayashi, Eiichi; Shimizu, Makoto; Tanabe, Takayoshi; Iwanaga, Shin-ichiro (JSR Corporation, Japan). Eur. Pat. Appl. EP 898201 A1 19990224

, 33 pp. DESIGNATED STATES: R: AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT, IE, SI, LT, LV, FI, RO. (English). CODEN: EPXXDW. APPLICATION: EP 1998-115537 19980818. PRIORITY: JP 1997-235495 19970818.

IT 24979-74-6, p-Hydroxystyrene-styrene copolymer

(photoresists contg. photosensitive compns.

generating both carboxylic and non-carboxylic acids and)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 10 OF 39 HCA COPYRIGHT 2005 ACS on STN
129:101835 Novel deep UV photoresist based on thermal
crosslinking and de-crosslinking of cross-linkable photoacid
generator. Moon, Seong-Yon; Koo, Jae-Sun; Oh, Seung-Hun; Lee,
Sang-Kyun; Kang, Shin-Ee (Polymer Mater. Lab., Chem. Sector,
Advanced Inst. Technol., Taejon, 305-380, S. Korea). Journal of
Photopolymer Science and Technology, 11(3), 439-444 (English)

1998. CODEN: JSTEEW. ISSN: 0914-9244. Publisher: Technical Association of Photopolymers, Japan.

IT 24979-74-6P, p-Hydroxystyrene-styrene copolymer (novel deep UV photoresist based on thermal crosslinking and de-crosslinking of cross-linkable photoacid generator)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 11 OF 39 HCA COPYRIGHT 2005 ACS on STN

128:237226 Positive-working photosensitive composition and preparation of phenolic compound or resin. Fujinomori, Susumu; Aogo, Toshiaki; Yamanaka, Tsukasa; Uenishi, Kazuya (Fuji Photo Film Co., Ltd., Japan). Jpn. Kokai Tokkyo Koho JP 10062996 A2

19980306 Heisei, 48 pp. (Japanese). CODEN: JKXXAF.

APPLICATION: JP 1996-217524 19960819.

IT 24979-74-6, p-Hydroxystyrene-styrene copolymer (photoresist compn. contg. phenolic compd. with acetal or ketal protective group)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8 $H_2C = CH - Ph$

L69 ANSWER 12 OF 39 HCA COPYRIGHT 2005 ACS on STN
128:161008 Positively working photosensitive composition with
high sensitivity and resolving power. Sato, Kenichiro; Uenishi,
Ichiya (Fuji Photo Film Co., Ltd., Japan). Jpn. Kokai Tokkyo Koho
JP 10010715 A2 19980116 Heisei, 52 pp. (Japanese).
CODEN: JKXXAF. APPLICATION: JP 1996-164696 19960625.

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 13 OF 39 HCA COPYRIGHT 2005 ACS on STN

128:28625 Positive-working photosensitive composition. Aoai,
Toshiaki; Yamanaka, Tsukasa; Uenishi, Kazuya (Fuji Photo Film Co.,
Ltd., Japan). U.S. US 5683856 A 19971104, 34 pp.,
Cont.-in-part of U.S. Ser. No. 525,157, abandoned. (English).
CODEN: USXXAM. APPLICATION: US 1996-634529 19960418. PRIORITY: JP
1994-252351 19941018; US 1995-525157 19950908.

IT 24979-74-6, p-Hydroxystyrene-styrene copolymer

24979-74-6, p-Hydroxystyrene-styrene copolymer (pos.-working photoresist compns. for lithog. plate and

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integrated circuit manuf. contg.)
RN 24979-74-6 HCA
CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)
CM 1
```

CRN CMF 2628-17-3

C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

CMF

C8 H8 O

ANSWER 14 OF 39 HCA COPYRIGHT 2005 ACS on STN 127:339242 Positive photosensitive composition. Aoai, Toshiaki; Kodama, Kunihiko; Uenishi, Kazuya; Yamanaka, Tsukasa (Fuji Photo Film Co., Ltd., Japan). Eur. Pat. Appl. EP 795786 A2 19970917, 96 pp. DESIGNATED STATES: R: BE, DE, FR, GB. (English). CODEN: EPXXDW. APPLICATION: EP 1997-103978 19970310. PRIORITY: JP 1996-53316 19960311; JP 1996-138918 19960531; JP 1996-167976 19960627; JP 1997-27111 19970210. ΙT 24979-74-6, p-Hydroxystyrene-styrene copolymer (pos. chem.-amplification photoresists contg. arylsulfonium arylsulfonate photoacid generators and) 24979-74-6 HCA RNPhenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX CN NAME) CM 1 CRN 2628-17-3

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 15 OF 39 HCA COPYRIGHT 2005 ACS on STN
127:212529 Chemically-amplified positive-working photoresist
composition with high resolution. Aogo, Toshiaki; Fujimori, Toru;
Yamanaka, Tsukasa; Uenishi, Kazuya (Fuji Photo Film Co., Ltd.,
Japan). Jpn. Kokai Tokkyo Koho JP 09197661 A2 19970731
Heisei, 67 pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP
1996-9582 19960123.

IT 24979-74-6, p-Hydroxystyrene-styrene copolymer (alkali-sol.; chem.-amplified pos.-working photoresist with high resoln. and transparency to deep UV light)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM _ 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8 $H_2C = CH - Ph$

L69 ANSWER 16 OF 39 HCA COPYRIGHT 2005 ACS on STN

127:154652 Negative-working radiation-sensitive resist composition. Ikezaki, Yoji; Yamachika, Mikio; Ota, Toshiyuki; Tsuji, Akira (Japan Synthetic Rubber Co., Ltd., Japan). Jpn. Kokai Tokkyo Koho JP 09166870 A2 19970624 Heisei, 14 pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP 1995-347019 19951214.

IT **24979-74-6**, p-Hydroxystyrene-styrene copolymer (neg.-working radiation-sensitive **resist** compn.)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 17 OF 39 HCA COPYRIGHT 2005 ACS on STN

127:115294 Resist coating solution, its preparation, and negative-working resist composition using it. Ishikawa, Kiyoshi; Omori, Katsumi; Sato, Mitsuru; Iguchi, Etsuko; Kaneko, Fumitake; Nakayama, Toshimasa (Tokyo Ohka Kogyo Co., Ltd., Japan). Jpn. Kokai Tokkyo Koho JP 09138503 A2 19970527 Heisei, 7 pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP 1995-295571 19951114.

IT **24979-74-6**, VPS 2515

(neg.-working resist compn. contg. amine and hydroxy-contg. resin)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 18 OF 39 HCA COPYRIGHT 2005 ACS on STN

125:342917 Positively working **photosensitive** resin composition containing acid-decomposable dissolution inhibitor. Yamanaka, Tsukasa; Aoso, Toshiaki (Fuji Photo Film Co Ltd, Japan). Jpn. Kokai Tokkyo Koho JP 08220762 A2 19960830 Heisei, 49 pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP 1995-25531 19950214.

IT **24979-74-6**, Maruka Lyncur CST 70

(pos. working photosensitive resin compn. contg. acid-decomposable dissoln. inhibitor)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 19 OF 39 HCA COPYRIGHT 2005 ACS on STN

125:342905 Positive- and negative-working radiation-sensitive resin compositions. Oota, Yoshihisa; Natsui, Tooru; Makita, Minoru; Yamachika, Mikio (Japan Synthetic Rubber Co Ltd, Japan). Jpn. Kokai Tokkyo Koho JP 08211598 A2 19960820 Heisei, 21 pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP 1995-39420 19950206.

IT **24979-74-6**, p-Hydroxystyrene-styrene copolymer (radiation-sensitive **resist** compn. contg. thiosulfonate)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEXNAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 20 OF 39 HCA COPYRIGHT 2005 ACS on STN 125:342878 Radiation-sensitive composition containing plasticizer. Padmanaban, Munirathna; Kinoshita, Yoshiaki; Okazaki, Hiroshi;

Masuda, Seiya; Kawasaki, Natsumi; Funato, Satoru; Pawlowski, Georg (Hoechst Industry Limited, Japan). Eur. Pat. Appl. EP 735422 A1 19961002, 14 pp. DESIGNATED STATES: R: DE, FR, GB. (English). CODEN: EPXXDW. APPLICATION: EP 1996-103906 19960312. PRIORITY: JP 1995-94299 19950328.

IT **24979-74-6**, 4-Hydroxystyrene-styrene copolymer (radiation-sensitive compns. for lithog. contg. plasticizers and polyacetals and)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA-INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 21 OF 39 HCA COPYRIGHT 2005 ACS on STN

125:45129 Radiation-sensitive composition. Padmanaban, Munirathna; Suehiro, Natsumi; Kinoshita, Yoshiaki; Funato, Satoru; Masuda, Seiya; Okazaki, Hiroshi; Pawlowski, Georg (Hoechst Japan Limited, Japan). Eur. Pat. Appl. EP 710885 Al 19960508, 17 pp.

DESIGNATED STATES: R: DE, FR, GB. (English). CODEN: EPXXDW. APPLICATION: EP 1995-117268 19951102. PRIORITY: JP 1994-269579 19941102.

IT **24979-74-6**, 4-Hydroxystyrene-styrene copolymer (chem. amplified **photoresists** contg. phenolic or polyphenolic compds. and)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 22 OF 39 HCA COPYRIGHT 2005 ACS on STN

125:45127 Positive chemically amplified resist composition and method for producing compounds used therein. Aoai, Toshiaki; Fujimori, Toru (Fuji Photo Film Co., Ltd., Japan). Eur. Pat. Appl. EP 709736 A1 19960501, 78 pp. DESIGNATED STATES: R: BE, DE. (English). CODEN: EPXXDW. APPLICATION: EP 1995-116815 19951025. PRIORITY: JP 1994-262790 19941026.

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 23 OF 39 HCA COPYRIGHT 2005 ACS on STN

125:45124 Positive-working photosensitive composition. Aoai,
Toshiaki; Yamanaka, Tsukasa; Uenishi, Kazuya (Fuji Photo Film Co.,
Ltd., Japan). Eur. Pat. Appl. EP 708368 A1 19960424, 78
pp. DESIGNATED STATES: R: BE, DE. (English). CODEN: EPXXDW.
APPLICATION: EP 1995-114054 19950907. PRIORITY: JP 1994-252351
19941018.

IT 24979-74-6, Styrene-p-hydroxystyrene copolymer (lithog. plate manuf. and resist pattern formation using pos.-working photosensitive compns. contg.)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 24 OF 39 HCA COPYRIGHT 2005 ACS on STN
124:131535 Chemical amplification-type resist composition.
Nakano, Yoshiko; Takeyama, Naomoto; Ueda, Juji; Kusumoto, Takehiro;
Ueki, Hiromi (Sumitomo Chemical Co., Ltd., Japan). Jpn. Kokai
Tokkyo Koho JP 07244378 A2 19950919 Heisei, 6 pp.

(Japanese). CODEN: JKXXAF. APPLICATION: JP 1994-34836 19940304. IT 24979-74-6, Maruka Lyncur CST 70

(chem. amplification-type resist contg. hydroxyimide sulfonate as photosensitive acid generator)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 25 OF 39 HCA COPYRIGHT 2005 ACS on STN

124:101862 Antireflection substrate material for underlayer of photosensitive resin. Takeyama, Naomiki; Kusumoto, Takehiro; Yamamoto, Shigeki; Oka, Hiromi; Nakano, Yoshiko (Sumitomo Chemical Co., Ltd., Japan). Jpn. Kokai Tokkyo Koho JP 07247401 A2 19950926 Heisei, 7 pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP 1994-41022 19940311.

IT **24979-74-6**, Maruka Lyncur CST 70

(resist component; antireflection substrate material for underlayer of photosensitive resin)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CRN 100-42-5 CMF C8 H8

H₂C== CH- Ph

L69 ANSWER 26 OF 39 HCA COPYRIGHT 2005 ACS on STN

124:71616 Negative-working radiation-sensitive **resist** composition and fine pattern formation using it. Kataoka, Mutsuo; Asano, Masaya (Toray Industries, Japan). Jpn. Kokai Tokkyo Koho JP 07219227 A2 **19950818** Heisei, 10 pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP 1994-13458 19940207.

IT 24979-74-6, p-Hydroxystyrene-styrene copolymer (CST 50; neg.-working resist compn. contg. alkali-sol. resin and quinonediazide compd.)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 27 OF 39 HCA COPYRIGHT 2005 ACS on STN

122:20516 Photopolymerizing compositions useful as photoresists. Ikeda, Tomoyuki; Inasawa, Kenji; Goto, Yoshitaka (Nippon Oils & Fats Co Ltd, Japan). Jpn. Kokai Tokkyo Koho JP 06202326 A2 19940722 Heisei, 6 pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP 1992-348642 19921228.

IT 24979-74-6, p-Hydroxystyrene-styrene copolymer (photoresist compn. contg. maleic anhydride-styrene copolymer and hydroxystyrene copolymer)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 28 OF 39 HCA COPYRIGHT 2005 ACS on STN

122:20514 Photopolymerizing compositions useful as
photoresists. Ikeda, Tomoyuki; Inasawa, Kenji; Goto,
Yoshitaka (Nippon Oils & Fats Co Ltd, Japan). Jpn. Kokai Tokkyo
Koho JP 06202322 A2 19940722 Heisei, 6 pp. (Japanese).
CODEN: JKXXAF. APPLICATION: JP 1992-348644 19921228.

IT 24979-74-6, p-Hydroxystyrene-styrene copolymer (photoresist compn. contg. hydroxystyrene copolymer and acrylate crosslinking agent)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 29 OF 39 HCA COPYRIGHT 2005 ACS on STN

121:289694 Photopolymerizing compositions useful for photoresists. Ikeda, Tomoyuki; Inasawa, Kenji; Goto, Yoshitaka (Nippon Oils & Fats Co Ltd, Japan). Jpn. Kokai Tokkyo Koho JP 06202327 A2 19940722 Heisei, 6 pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP 1992-348643 19921228.

IT 24979-74-6, p-Hydroxystyrene-styrene copolymer (photoresist compn. contg. hydroxystyrene copolymer and acrylate crosslinking agent and photopolymn. initiator)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 30 OF 39 HCA COPYRIGHT 2005 ACS on STN
121:96051 Negative-working photoresists compositions useful
for making semiconductor circuits. Kitaori, Tomoyuki; Koyanagi,
Takao; Fukunaga, Masanori (Nippon Kayaku Kk, Japan). Jpn. Kokai
Tokkyo Koho JP 06035194 A2 19940210 Heisei, 5 pp.

(Japanese). CODEN: JKXXAF. APPLICATION: JP 1992-213264 19920720.

IT 24979-74-6, Maruka Lyncur CST 70 (photoresist from)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 31 OF 39 HCA COPYRIGHT 2005 ACS on STN
120:334985 Negative-working photoresist compositions with high
photosensitivity. Tochisawa, Tetsuaki; Kunyoshi, Yasuo;
Matsumura, Masako; Kikuchi, Hideo (Toyo Gosei Kogyo Kk, Japan).
Jpn. Kokai Tokkyo Koho JP 05341507 A2 19931224 Heisei, 12
pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP 1992-153383
19920612.

IT 24979-74-6, p-Hydroxystyrene-styrene copolymer (reaction of, with azidechalkonesulfonyl chloride)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 32 OF 39 HCA COPYRIGHT 2005 ACS on STN
120:120769 Process for purifying vinylphenol polymers for use as
photoresist materials. Matsumoto, Tadashi; Akaho, Mitsuru
(Maruzen Petrochemical Co., Ltd., Japan). Eur. Pat. Appl. EP 544325
A1 19930602, 11 pp. DESIGNATED STATES: R: CH, DE, FR,
GB, LI, NL. (English). CODEN: EPXXDW. APPLICATION: EP 1992-120311
19921127. PRIORITY: JP 1991-339728 19911128.

L69 ANSWER 33 OF 39 HCA COPYRIGHT 2005 ACS on STN
119:128428 Radiation-sensitive compositions useful as resists.

Murata, Makoto; Oota, Toshuki; Isamoto, Yoshitsugu; Miura, Takao
(Japan Synthetic Rubber Co Ltd, Japan). Jpn. Kokai Tokkyo Koho JP
05066563 A2 19930319 Heisei, 14 pp. (Japanese). CODEN:
JKXXAF. APPLICATION: JP 1991-252788 19910905.

IT 24979-74-6P, p-Hydroxystyrene-styrene copolymer (prepn. and reaction of, with succinic anhydride and dihydropyran)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 34 OF 39 HCA COPYRIGHT 2005 ACS on STN

119:128416 Negative-working radiation-sensitive composition and radiation-sensitive recording material produced therewith. Pawlowski, Georg; Dammel, Ralph; Roeschert, Horst; Meier, Winfried; Spiess, Walter; Przybilla, Klaus Juergen (Hoechst A.-G., Germany). Eur. Pat. Appl. EP 525625 Al 19930203, 16 pp. DESIGNATED STATES: R: BE, CH, DE, FR, GB, IT, LI. (German). CODEN: EPXXDW. APPLICATION: EP 1992-112559 19920722. PRIORITY: DE 1991-4125042 19910729.

IT 24979-74-6, 4-Hydroxystyrene-styrene copolymer (neg.-working photosensitive compn. cong)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 35 OF 39 HCA COPYRIGHT 2005 ACS on STN
114:153929 Photopolymerizable compositions and recording
materials containing them. Schneller, Arnold; Emmelius, Michael
(Hoechst A.-G., Germany). Ger. Offen. DE 3839366 A1
19900523, 9 pp. (German). CODEN: GWXXBX. APPLICATION: DE
1988-3839366 19881122.

IT 24979-74-6, p-Hydroxystyrene-styrene copolymer (as binder in photopolymerizable compn.)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 36 OF 39 HCA COPYRIGHT 2005 ACS on STN
113:106450 Heat-resistant photoresist composition for far
ultraviolet or excimer laser beam. Totoko, Masaaki; Yamamoto,
Takashi; Nagaoka, Keiko; Kyota, Toru (Tosoh Corp., Japan). Jpn.
Kokai Tokkyo Koho JP 02015270 A2 19900118 Heisei, 7 pp.
(Japanese). CODEN: JKXXAF. APPLICATION: JP 1988-165127 19880704.

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 37 OF 39 HCA COPYRIGHT 2005 ACS on STN
112:207982 Photoresist compositions. Todoko, Masaaki; Kyota,
Toru; Yamamoto, Takashi; Nagaoka, Tsuneko (Tosoh Corp., Japan).
Jpn. Kokai Tokkyo Koho JP 01293339 A2 19891127 Heisei, 8
pp. (Japanese). CODEN: JKXXAF. APPLICATION: JP 1988-123929
19880523.

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CRN 100-42-5 CMF C8 H8

 $H_2C \longrightarrow CH - Ph$

L69 ANSWER 38 OF 39 HCA COPYRIGHT 2005 ACS on STN

104:43202 Radiation-sensitive mixture from acid-cleavable compounds.

Schneller, Arnold; Herwig, Walter; Erbes, Kurt (Hoechst A.-G., Fed. Rep. Ger.). Ger. Offen. DE 3406927 A1 19850829, 28 pp.

(German). CODEN: GWXXBX. APPLICATION: DE 1984-3406927 19840225.

IT 24979-74-6

(photoresist compn. contg. acid-cleavable compd. and)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$

L69 ANSWER 39 OF 39 HCA COPYRIGHT 2005 ACS on STN

92:164689 **Photosensitive** polymers. Yamaguchi, Hiroyoshi; Iwaki, Akio; Kita, Noriyasu; Sasazawa, Tatsuya (Konishiroku Photo Industry Co., Ltd., Japan). Brit. UK Pat. Appl. GB 2018779

19791024, 14 pp. (English). CODEN: BAXXDU. APPLICATION:

GB 1979-12930 19790412.

IT 24979-74-6P

(manuf. and esterification of, by azidocinnamylidenecyanoacetic acid chloride)

RN 24979-74-6 HCA

CN Phenol, 4-ethenyl-, polymer with ethenylbenzene (9CI) (CA INDEX NAME)

CM 1

CRN 2628-17-3 CMF C8 H8 O

CM 2

CRN 100-42-5 CMF C8 H8

 $H_2C = CH - Ph$